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<b>UTILITY PATENT APPLICATION TRANSMITTAL</b> (Only for new nonprovisional applications under 37 C.F.R. § 1.53(b))	Attorney Docket No.	98-0645.1
	First Inventor or Application Identifier	TONGBI JIANG
	Title	METHOD FOR FABRICATING BGA PACKAGE...
	Express Mail Label No.	EE 697 314 553US

<b>APPLICATION ELEMENTS</b> See MPEP chapter 600 concerning utility patent application contents.	<b>ADDRESS TO:</b> Assistant Commissioner for Patents Box Patent Application Washington, DC 20231
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1. ☒ \* Fee Transmittal Form (e.g., PTO/SB/17)  
(Submit an original and a duplicate for fee processing)
2. ☒ Specification [Total Pages **24**]  
(preferred arrangement set forth below)
  - Descriptive title of the Invention
  - Cross References to Related Applications
  - Statement Regarding Fed sponsored R & D
  - Reference to Microfiche Appendix
  - Background of the Invention
  - Brief Summary of the Invention
  - Brief Description of the Drawings (if filed)
  - Detailed Description
  - Claim(s)
  - Abstract of the Disclosure
3. ☒ Drawing(s) (35 U.S.C. 113) [Total Sheets **6**]
4. Oath or Declaration [Total Pages **3**]
  - a. ☐ Newly executed (original or copy)
  - b. ☒ Copy from a prior application (37 C.F.R. § 1.63(d))  
(for continuation/divisional with Box 17 completed)  
[Note Box 5 below]
    - i. ☐ DELETION OF INVENTOR(S)  
Signed statement attached deleting inventor(s) named in the prior application, see 37 C.F.R. §§ 1.63(d)(2) and 1.33(b).
5. ☒ Incorporation By Reference (useable if Box 4b is checked)  
The entire disclosure of the prior application, from which a copy of the oath or declaration is supplied under Box 4b, is considered to be part of the disclosure of the accompanying application and is hereby incorporated by reference therein.

6. ☐ Microfiche Computer Program (Appendix)
7. Nucleotide and/or Amino Acid Sequence Submission (if applicable, all necessary)
  - a. ☐ Computer Readable Copy
  - b. ☐ Paper Copy (identical to computer copy)
  - c. ☐ Statement verifying identity of above copies

ACCOMPANYING APPLICATION PARTS	
8. <input type="checkbox"/> Assignment Papers (cover sheet & document(s))	
9. <input type="checkbox"/> 37 C.F.R. § 3.73(b) Statement (when there is an assignee)	<input type="checkbox"/> Power of Attorney
10. <input type="checkbox"/> English Translation Document (if applicable)	
11. <input checked="" type="checkbox"/> Information Disclosure Statement (IDS)/PTO-1449	<input checked="" type="checkbox"/> Copies of IDS Citations
12. <input checked="" type="checkbox"/> Preliminary Amendment	
13. <input checked="" type="checkbox"/> Return Receipt Postcard (MPEP 503) (Should be specifically itemized)	
14. <input type="checkbox"/> * Small Entity Statement(s) (PTO/SB/09-12)	<input type="checkbox"/> Statement filed in prior application, Status still proper and desired
15. <input type="checkbox"/> Certified Copy of Priority Document(s) (if foreign priority is claimed)	
16. <input checked="" type="checkbox"/> Other:	<b>CHANGE OF ADDRESS FOR CORRESPONDENCE; EXPRESS MAIL CERT.</b>

\* NOTE FOR ITEMS 1 & 14: IN ORDER TO BE ENTITLED TO PAY SMALL ENTITY FEES, A SMALL ENTITY STATEMENT IS REQUIRED (37 C.F.R. § 1.27), EXCEPT IF ONE FILED IN A PRIOR APPLICATION IS RELIED UPON (37 C.F.R. § 1.28).

17. If a CONTINUING APPLICATION, check appropriate box, and supply the requisite information below and in a preliminary amendment:

<input type="checkbox"/> Continuation	<input type="checkbox"/> Divisional	<input checked="" type="checkbox"/> Continuation-in-part (CIP)	of prior application No: <b>09, 191,215</b>
Prior application information: Examiner <b>Nadav, O.</b>		Group / Art Unit: <b>2811</b>	

18. CORRESPONDENCE ADDRESS					
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Signature		Date	<b>March 1, 1999</b>

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**EXPRESS MAIL #EE 697 314 553US**  
**Date of Deposit: March 1, 1999**

**CERTIFICATE OF MAILING BY EXPRESS MAIL**  
**UNDER 37 C.F.R. §1.10**

I hereby certify that this divisional application in the names of TONGBI JIANG and EDWARD SCHROCK entitled "METHOD FOR FABRICATING BGA PACKAGE USING SUBSTRATE WITH PATTERNED SOLDER MASK OPEN IN DIE ATTACH AREA" along with a Utility Patent Application Transmittal; a Fee Transmittal; a check in the amount of \$838.00 for the filing fee; a copy of the patent specification (pages 1-24), drawings (6 sheets), a "Declaration and Power of Attorney for Patent Application (Joint Inventors)" in the prior application (Serial No. 09/191,215); a Change of Address for Correspondence; a Preliminary Amendment dated March 1, 1999 (pages 1-2); an Information Disclosure Statement along with copies of the cited references; and a return receipt postcard are being deposited with the United States Postal Service "Express Mail Post Office to Addressee" service under 37 C.F.R. §1.10 on the date indicated above in an envelope addressed to the Assistant Commissioner of Patents, BOX PATENT APPLICATION, Washington, D.C. 20231.

DATED this 1st day of March, 1999.

  
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Docket No. 98-0645.1

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re application of:

TONGBI JIANG  
EDWARD SCHROCK

Art Unit: 2811

Serial No.:

Division of Serial No.  
09/191,215 filed November 12, 1998

Filing Date: March 1, 1999

Examiner: Nadav, O.

Title: METHOD FOR FABRICATING BGA PACKAGE  
USING SUBSTRATE WITH PATTERNED  
SOLDER MASK OPEN IN DIE ATTACH AREA

Attorney Docket No.: 98-0645.1

**PRELIMINARY AMENDMENT  
SUBMITTED WITH CONTINUING APPLICATION  
UNDER 37 CFR 1.53(b)  
March 1, 1999**

Commissioner of Patents and Trademarks  
BOX PATENT APPLICATION  
Washington, D.C. 20231

Sir:

This Preliminary Amendment is being filed with a continuing application (division) under 37 CFR 1.53(b). Please amend the captioned case as follows.

In the Specification

On page 2, line 1, please add the following:

--Cross Reference To Related Applications

This application is a division of application serial no. 09/191,215, filed on November 12, 1998.--

In the Claims

Please cancel claims 1-23.

## REMARKS

This continuing application is being filed as a result of the Restriction Requirement contained in the Office Action of January 12, 1999 of parent application serial no. 09/191,215. The amendment cancels "method" claims 1-23 originally filed with the parent case.

An Information Disclosure Statement is also being submitted with the continuing application. Favorable consideration and allowance of claims 24-36 is respectfully requested. Should any issues arise that will advance this case to allowance, the Examiner is asked to contact the undersigned by telephone.

DATED this 1st day of March, 1999.

Respectfully submitted:



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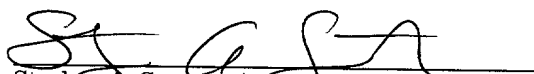
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Stephen A. Gratton, Attorney for Applicant

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November 12, 1998  
Date of Signature

Stephen A. Gratton  
Attorney for Applicants

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

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**APPLICATION FOR LETTERS PATENT**

**METHOD FOR FABRICATING BGA  
PACKAGE USING SUBSTRATE  
WITH PATTERNED SOLDER MASK  
OPEN IN DIE ATTACH AREA**

**INVENTORS**

**TONGBI JIANG  
EDWARD SCHROCK**

**ATTORNEY'S DOCKET NO. 98-645**

## Field of the Invention

This invention relates generally to semiconductor packaging and specifically to a method for fabricating BGA packages using a substrate having a patterned solder mask with an open die attach area.

## Background of the Invention

One type of semiconductor package is referred to as a BGA package. BGA packages were developed to provide a higher lead count, and a smaller foot print, than conventional plastic or ceramic semiconductor packages. A BGA package includes an area array of solder balls that permit the package to be surface mounted to a printed circuit board (PCB) or other electronic component.

One type of prior art BGA package 10 is illustrated in Figure 1A. The BGA package 10 includes a substrate 12, a semiconductor die 16 mounted to the substrate 12, and an encapsulating resin 38 which encapsulates the die 16. As shown in Figure 1B, the substrate 12 is initially a segment 32 of a panel 30. The panel 30 is similar to a lead frame used in the fabrication of conventional plastic semiconductor packages. The panel 30 includes multiple substrates 12 and is used to fabricate multiple BGA packages 10. Following the fabrication process for the BGA packages 10, the panel 30 is singulated into individual BGA packages 10.

Typically, the substrate 12 comprises a reinforced polymer laminate material, such as bismaleimide triazine (BT), or a polyimide resin. As shown in Figure 1A, the substrate 12 includes a planar die attach surface 22. During a die attach step of the fabrication process, the die 16 is adhesively bonded to the substrate 12 using an adhesive layer 34.

In addition to the die attach surface 22, the substrate 12 includes an opposing conductor surface 24 wherein

conductors 18 are formed in a required pattern. An opening 26 in the substrate 12 provides access for wire bonding wires 28 to the conductors 18, and to bond pads (not shown) on the die 16. In the type of BGA package 10 illustrated in Figure 1A, the die 16 is adhesively bonded face down to the die attach surface 22, with the bond pads on the die 16 aligned with the opening 26. Following the wire bonding step, an encapsulating resin 38 such as a Novoloc based epoxy, is molded onto the substrate 12 to encapsulate the die 16. In addition, a glob top 40 or other encapsulant can be formed over the wires 28 for protection. In some types of BGA packages the die 16 is attached back side down to the substrate 12, and the wire bonded wires 28 are encapsulated in the encapsulating resin 38.

The substrate 12 also includes a solder mask 20A formed on the conductor surface 24 and on the conductors 18. The solder mask 20A includes a pattern of via openings 25, wherein an array of solder balls 14 are located. During a solder ball bonding step, the solder balls 14 are bonded to ball bonding pads 31 on the conductors 18. Typically, solder ball bonding is performed by applying flux to the ball bonding pads 31, and to the solder balls 14. The solder balls 14 are then placed in the via openings 25, and the assembly is placed in an oven wherein the solder is reflowed to form a metallurgical solder bond. The solder mask 20A comprises an electrically insulating, low surface tension material, which prevents bridging of the solder material, and shorting between the solder balls 14 in the completed BGA package 10. In addition, the solder mask 20A helps to position the solder balls 14 for the solder reflow process.

Typically, the solder mask 20A comprises a photoimageable material, that can be blanket deposited as a wet or dry film, exposed through a mask, developed and then cured. Wet films are preferred because of their moisture

resistance and low cost. Exposure and development of the solder mask 20A forms the via openings 25 in a required pattern and with required diameters. In addition, exposure and development of the solder mask 20A removes the mask material from the conductors 18 in a wire bonding area 36, wherein the wires 28 are wire bonded to the conductors 18.

In addition to the solder mask 20A being formed on the conductors 18, a solder mask 20B is also formed on the die attach surface 22. In general, the panel 30 is constructed with the solder mask 20B on the die attach surface 22 because the mask material is initially blanket deposited on all exposed surfaces of the panel 30 to form the solder mask 20A. For example, a spray coater or a curtain coater, can be used to blanket deposit the mask material on both the die attach surface 22, and on the conductor surface 24 of the substrates 12.

The presence of the solder mask 20B on the die attach surface 22 of the substrate 12 can cause problems in the BGA package 10. Firstly, the adhesive layer 34 which bonds the die 16 to the die attach surface 22 must be formed on the solder mask 20B. In general the solder mask 20B has a smooth surface, and a low surface tension. Accordingly, the adhesive bond between the die 16 and the solder mask 20B can be substandard. This can cause the die 16 to pop loose from the die attach surface 22.

Secondly, the solder mask 20B has hydrophilic properties, and tends to attract moisture. In order to drive off the moisture, along with solvents and other volatile compounds, a prebaking step can be performed on the solder mask 20B. However, this extra process step is sometimes not sufficient to prevent trapped moisture in the completed BGA package 10. Thirdly, the solder mask 20B can delaminate from the substrate 12 causing cracks to form in the BGA package 10.



In view of these and other deficiencies in conventional methods for fabricating BGA packages, improvements in BGA substrates, and in fabrication methods for BGA packages, are needed in the art.

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### Summary of the Invention

In accordance with the present invention, an improved method for fabricating BGA packages, and an improved substrate for fabricating BGA packages, are provided.

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The method, simply stated, comprises forming a substrate having a solder mask that substantially covers both major surfaces thereof, but which is patterned to leave a die attach area on the substrate open. The open die attach area permits a semiconductor die to be bonded directly to the substrate, rather than to the solder mask. This improves adhesion of the die to the substrate, reduces trapped moisture, and prevents delamination of the solder mask in the die attach area.

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The substrate can comprise an electrically insulating material, such as bismaleimide triazine (BT). Initially, the substrate can be a segment of a panel which can be used to fabricate multiple BGA packages. The substrate includes a pattern of conductors formed on a first surface thereof, and a die attach area formed on an opposing second surface thereof. A first solder mask is formed on the first surface, and includes a pattern of via openings for attaching solder balls to ball bonding pads on the conductors. A second solder mask is formed on the second surface, and includes openings on the die attach area, permitting the die to be adhesively bonded directly to the substrate.

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In an illustrative embodiment, the die is adhesively bonded face down to the substrate. In addition, bond pads on the die are placed in electrical communication with a corresponding pattern of conductors on the substrate, by wire

bonding through openings in the substrate. Alternately, a flip chip process, or tape automated bonding, can be used to establish electrical communication between the die and the conductors.

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### Brief Description of the Drawings

Figure 1A is a schematic cross sectional view of a prior art BGA package taken along section line 1A-1A of Figure 1B;

10 Figure 1B is a plan view of a prior art panel containing a substrate for fabricating the BGA package shown in Figure 1A;

Figure 2A is a plan view of a panel containing multiple substrates constructed in accordance with the invention prior to formation of solder masks on the substrates;

15 Figure 2B is a bottom view of the panel;

Figure 2C is an enlarged portion of a substrate on the panel taken along section line 2C of Figure 2A;

Figure 2D is a cross sectional view of the substrate taken along section line 2D-2D of Figure 2C;

20 Figure 2E is a cross sectional view of the substrate taken along section line 2E-2E of Figure 2C;

Figures 3A-3D are schematic cross sectional views illustrating process steps during fabrication of the substrate;

25 Figure 4 is a bottom view of a panel containing multiple substrates and dice, with each substrate fabricated using the steps shown in Figures 3A-3D;

Figure 4A is an enlarged cross section view taken along section line 4A-4A of Figure 4 showing a semiconductor die adhesively bonded to a substrate on the panel;

30 Figure 5 is an enlarged plan view of the substrate on the panel;

Figure 5A is an enlarged cross sectional view of the substrate taken along section line 5A-5A of Figure 5;

Figure 5B is an enlarged cross sectional view taken along section line 5B-5B of Figure 5 showing a conductor on the substrate;

Figure 5C is an enlarged cross sectional view taken along section line 5C-5C of Figure 5 showing a ball bonding pad on the substrate;

Figure 5D is an enlarged cross sectional view taken along section line 5D-5D of Figure 5 showing a wire bonding pad on the substrate;

Figures 6A-6B are schematic cross sectional views illustrating steps during fabrication of a BGA package using the substrate; and

Figure 7 is a schematic cross sectional view of the completed BGA package.

#### Detailed Description of the Preferred Embodiments

Referring to Figures 2A-2E, a panel 42 containing a plurality of substrates 56 constructed in accordance with the invention is illustrated. In Figures 2A-2E, the panel 42 and substrates 56 are illustrated prior to formation of solder masks thereon.

Each substrate 56 is a segment of the panel 42, and will subsequently be separated from the adjacent substrates 56 to form a BGA package 62 (Figure 7). In the illustrative embodiment there are eighteen substrates 56 on the panel 42. However, this number is merely exemplary and the panel 42 can include a fewer or greater number of substrates 56. The panel 42 facilitates the fabrication process in that different operations, such as die attach, and wire bonding, can be performed at the same time on each of the substrates 56.

Each substrate 56 includes a first surface 44 (Figure 2A), and an opposing second surface 46 (Figure 2B). The first surface 44, and the second surface 46, are the major

planar surfaces of the substrates 56. Each substrate 56 also includes a pattern of conductors 48 formed on the first surface 44 thereof, and a corresponding die attach area 50 formed on the second surface 46 thereof.

5       The substrates 56 comprise an electrically insulating material such as an organic polymer resin reinforced with glass fibers. Suitable materials for the substrates 56 include bismaleimide-triazine (BT), epoxy resins (e.g., "FR-4" and "FR-5"), and polyimide resins. These materials can be  
10       formed with a desired thickness, and then punched, machined, or otherwise formed with a required peripheral configuration, and with required features. A representative thickness of the substrates 56 can be from about 0.2 mm to 1.6 mm.

15       As shown in Figure 2A, the panel 42 includes circular indexing openings 58 formed through the substrates 56 and proximate to the longitudinal edges of the panel 42. The indexing openings 58 permit the panel 42 to be handled by automated transfer mechanisms associated with chip bonders, wire bonders, molds, and trim machinery. In addition, the  
20       panel 42 includes elongated separation openings 60 which facilitate singulation of the substrates 56 on the panel 42 into separate BGA packages 62 (Figure 7). The substrates 56 also includes wire bonding openings 64 which provide access for wire bonding semiconductor dice 16 (Figure 4A) to the  
25       patterns of conductors 48 on the substrates 56.

Referring to Figure 2C, a single substrate 56 and the conductors 48 on the substrate 56 are shown in greater detail. The conductors 48 initially comprise a highly conductive metal layer, which is blanket deposited onto the  
30       substrate 56 (e.g., electroless or electrolytic plating), and then etched in required patterns. Alternately, an additive process, such as electroless deposition through a mask, can be used to form the conductors 48 in required patterns. A preferred metal for the conductors 48 is copper. Other

suitable metals for the conductors 48 include aluminum, titanium, tungsten, tantalum, platinum, molybdenum, cobalt, nickel, gold, and iridium. If desired, the substrate 56 and conductors 48 can be constructed from a commercially produced  
5 bi-material core, such as a copper clad bismaleimide-triazine (BT) core, available from Mitsubishi Gas Chemical Corp., Japan. A representative weight of the copper can be from 0.5 oz to 2 oz. per square foot.

As shown in Figure 2C, each conductor 48 includes a wire  
10 bonding pad 52 and a ball bonding pad 54. The wire bonding pads 52 can subsequently be plated with metals such as nickel and gold to facilitate the wire bonding process. The ball bonding pad 54 can also subsequently be plated with a solder flux to facilitate attachment of solder balls 88 (Figure 7)  
15 thereto.

As shown in Figure 2C, the panel 42 also includes a triangular metal segment 66, and a circular metal segment 68 formed on the first surface 44. The metal segments 66, 68 can comprise a same metal as the conductors 48. The  
20 triangular shaped metal segment 66 functions as a pin #1 indicators. The circular metal segment 68 functions as an alignment fiducial. As shown in Figure 2B, the panel 42 also includes a square metal segment 76 and a triangular metal segment 78 on the second surface 46. The square metal  
25 segment 76 function as a mold compound gate break. The triangular metal segment 78 functions as a pin #1 indicator.

Referring to Figures 3A-3D, steps in a method for forming a solder mask 80A (Figure 3C) on the first surface 44 (Figure 3A), and a solder mask 80B (Figure 3C) on the second  
30 surface 46 (Figure 3A) of the substrate 56 are illustrated. Although these steps are shown as being performed on a single substrate 56, it is to be understood that the steps are performed on each of the substrates 56 contained on the panel 42, substantially at the same time.

Initially, as shown in Figure 3A, the substrate 56 can be provided with the conductors 48 on the first surface 44, and the die attach area 50 on the second surface 46, substantially as previously described and shown in Figures 2A-2E. In addition, the die attach area 50 can include the wire bonding opening 64 formed through the substrate 56 to the patterns of conductors 48.

As shown in Figure 3B, a mask material 74A is blanket deposited on the first surface 44 and substantially covers the first surface 44. Similarly, a mask material 74B is blanket deposited on the second surface 46 and substantially covers the second surface 46 and conductors 48. Preferably, the mask materials 74A, 74B comprise a photoimageable dielectric material, such as a negative or positive tone resist. One suitable resist is commercially available from Taiyo America, Inc., Carson City, NV. under the trademark "PSR-4000". The "PSR-4000" resist can be mixed with an epoxy such as epoxy "720" manufactured by Ciba-Geigy (e.g., 80% PSR-4000 and 20% epoxy "720"). Another suitable resist is commercially available from Shipley under the trademark "XP-9500".

The mask materials 74A, 74B can be blanket deposited onto the substrate 56 using a suitable deposition process, such as by spraying the mask materials 74A, 74B through a nozzle onto the substrate 56, or by moving the substrate 56 through a curtain coater conveyor having curtains of mask materials 74A, 74B. A representative thickness of the mask materials 74A, 74B can be from about 1 mils to 4 mils. A representative weight of the mask materials 74A, 74B can be from about 0.32 oz - 0.42 oz (9-12 grams) per square foot.

Following blanket deposition of the mask materials 74A, 74B, a prebaking step can be performed to partially harden the mask materials 74A, 74B. For example, the mask materials 74A, 74B can be "prebaked" at about 95°C for about 15

minutes. Following prebaking, the mask materials 74A, 74B can be exposed in a desired pattern using a suitable mask, and a conventional UV aligner. A representative UV dose can be about 165mJ/cm<sup>2</sup>.

5        Following exposure of the mask materials 74A, 74B a developing step can be performed. The developing step can be performed using a suitable developing solution such as a 1 to 1.5 percent solution of sodium monohydrate (Na<sub>2</sub>CO<sub>3</sub> - H<sub>2</sub>O), or  
10        potassium carbonate monohydrate (K<sub>2</sub>CO<sub>3</sub>-H<sub>2</sub>O). Following the developing step, the mask materials 74A, 74B can be rinsed, dried and cured. Curing can be performed by exposure to UV at a desired power (e.g., 3-5 J/cm<sup>2</sup>), or by heating to a desired temperature (e.g., 150-155°C) for a desired time (e.g., one hour).

15        As shown in Figure 3C, exposing and developing the mask material 74A forms the solder mask 80A on the first surface 44 of the substrate 56. The solder mask 80A includes via openings 82 to the conductors 48. In addition, the solder mask 80A includes an opening 84 for wire bonding to the  
20        conductors 48.

As also shown in Figure 3C, exposing and developing the mask material 74B forms the solder mask 80B on the second surface 46 of the substrate 56. The solder mask 80B includes a die attach opening 86 having an outline that is slightly  
25        larger than the outline of the semiconductor die 16.

As shown in Figure 3D, the die attach opening 86 permits the die 16 to be placed there through, and bonded directly to the substrate 56 using an adhesive layer 72. The adhesive layer 72 can comprise a filled epoxy, an unfilled epoxy, an  
30        acrylic, or a polyimide material. A conventional die attacher can be used to form the adhesive layer 72 and adhesively bond the die 16 to the substrate 56.

In Figures 4 and 4A, the panel 42 is illustrated following formation of the solder masks 80A and 80B, and

following attachment of the dice 16 to the substrates 56. As previously stated, the die attach openings 86 permit the dice 16 to be bonded directly to the substrates 56. Bonding the dice 16 directly to the substrates 56, rather than to a solder mask, as in the prior art, provides the following benefits.

1. Improved adhesion of the die 16 to the substrate 56 in the completed package 62 (Figure 7).

2. Improved heat transfer between the die 16 and the substrate 56 in the completed package 62 (Figure 7).

3. Less trapping of moisture between the die 16 and the substrate 56.

4. No possibility of the solder mask 80B delaminating from the substrate 56 in the die attach area 50, as the solder mask 80B is open in this area.

In Figures 5-5D, the substrate 56, and the first surface 44 thereof, are illustrated following formation of the solder mask 80A thereon. As shown in Figure 5A, the solder mask 80A substantially covers the first surface 44 of the substrate 56. As shown in Figure 5B, the solder mask 80A also substantially covers the conductors 48 on the substrate 56. As shown in Figure 5C, the solder mask 80A includes via openings 82 to the ball bonding pads 54 on the conductors 48. As shown in Figure 5D, the openings 86 in the solder mask 80A exposes the wire bonding pads 52 of the conductors 48 for wire bonding.

Referring to Figures 6A-6B steps in a method for fabricating the BGA package 62 (Figure 7) using the substrate 56 with the solder masks 80A, 80B thereon, are illustrated. As before these steps are shown being performed on a single substrate, although in actual practice the steps will be performed on multiple substrates 56 contained on the panel 42 (Figure 2A).



As shown in Figure 6A, following attachment of the die 16 to the substrate 56, wires 94 can be wire bonded to the wire bonding pads 52, and to corresponding bond pads on the die 16. A conventional wire bonder can be used to perform the wire bonding step. Alternately, instead of wire bonding, a flip chip process (e.g., C4), or a TAB bonding process, can be used to electrically connect the die 16 to the conductors 48. In addition, although in the illustrative embodiment, the die 16 is mounted face down to the substrate 56, the die 16 can alternately be back bonded to the substrate 56, and wire bonded to conductors located on a same surface of the substrate 56 as the die 16.

As also shown in Figure 6A, following wire bonding, an encapsulating resin 90 can be formed on the die 16 and on the substrate 56. The encapsulating resin 90 can comprise a Novolac based epoxy formed in a desired shape using a transfer molding process, and then cured using an oven. Also, if desired, a glob top 92 can be formed on the wires 94.

As shown in Figure 6B, following formation of the encapsulating resin 90, solder balls 88 can be bonded to the ball bonding pads 54 of the conductors 48. A solder reflow process can be used to bond the solder balls 88 to the ball bonding pads 54. Prior to the solder reflow process, solder flux can be deposited on the ball bonding pads 54 and on the solder balls 88. The solder balls 88 can then be placed on the ball bonding pads 54, and a furnace used to form metallurgical solder joints between the solder balls 88 and the ball bonding pads 54. During bonding of the solder balls 88, the via openings 82 in the solder mask 80A facilitate alignment of the solder balls 88 to the ball bonding pads 54. In addition, in the completed BGA package 62, the solder mask 80A insulates adjacent solder balls 88 and insulates the conductors 48 from the solder balls.

Referring to Figure 7, the BGA package 62 fabricated using the substrate 56 is illustrated. The BGA package 62 includes the semiconductor die 16 bonded directly to the substrate 56. The opening 86 in the solder mask 80B allows the die 16 to be bonded directly to the substrate 56. In addition, the BGA package 62 includes solder balls 88 placed through the via openings 82 in solder mask 80A and bonded to the ball bonding pads 54 on the conductors 48. Further, the BGA package 62 includes the encapsulating resin 90 which encapsulates the die 16. Still further, the BGA package 62 includes wires 94 wire bonded to the die 16 and to wire bonding pads 52. The BGA package 62 also includes the glob top 92 encapsulating the wires 94.

Steps in a method for fabricating the BGA package 62 can be summarized as follows.

1. Providing the substrate 56 with the first surface 44 and the second surface 46.

2. Providing the pattern of conductors 48 on the first surface 44. Each conductor 48 including the wire bonding pad 52 and the ball bonding pad 54.

3. Providing the die attach area 50 on the second surface 46 of the substrate 56.

4. Depositing the photoimageable mask material 74A on the first surface 44 and on the conductors 48.

5. Depositing the photoimageable mask material 74B on the second surface 46 and on the die attach area 50.

6. Exposing and developing the mask material 74A on the first surface 44 to form the first solder mask 80A having the via openings 82 to the ball bonding pads 54, and the opening 84 to the wire bonding pads 52.

7. Exposing and developing the mask material 74B on the second surface 46 to form the second solder mask 80B having the opening 86 to the die attach area 50.

8. Placing the semiconductor die 16 through the opening 86 in the die attach area 50.

9. Attaching the die 16 to the die attach area 50 using the adhesive layer 72.

5 10. Wire bonding wires 94 to the die 16 and to the wire bonding pads 52 on the conductors 48.

11. Forming the encapsulating resin 90 on the die 16 and the substrate 56.

10 12. Bonding solder balls 88 to the ball bonding pads 54 with the solder mask 80A locating and insulating the solder balls 88.

13. With the substrate 56 contained on the panel 42 a singulating step can be performed by cutting, shearing or punching the substrate 56 from the panel 42.

15 14. Thus the invention provides a method for fabricating BGA packages using a substrate having a solder mask that is open in die attach areas. Although the invention has been described with reference to certain preferred embodiments, as will be apparent to those skilled in the art, certain changes and modifications can be made without departing from the scope of the invention, as defined by the following claims.

20

We Claim:

1. A method for fabricating a semiconductor package comprising:

5 providing a substrate having a first surface with a die attach area thereon;

depositing a photoimageable mask material on the first surface and on the die attach area;

10 exposing and developing the mask material to form a mask having an opening on the die attach area;

placing a semiconductor die in the opening; and

bonding the die to the die attach area.

15 2. The method of claim 1 further comprising exposing and developing the mask material to form via openings in the mask for bonding solder balls to the substrate.

20 3. The method of claim 1 wherein bonding the die comprises forming an adhesive layer between the die and the substrate.

4. A method for fabricating a semiconductor package comprising:

25 providing a substrate having a first surface;

depositing a photoimageable mask material on the substrate, the mask material substantially covering the first surface;

30 exposing and developing the mask material to form a mask having an opening which defines a die attach area on the first surface; and

bonding a semiconductor die to the die attach area by forming an adhesive layer between the die and substrate.

5. The method of claim 4 further comprising depositing the mask material on a second surface of the substrate and exposing and developing the mask material to form a second mask on the second surface.

6. The method of claim 4 further comprising providing the substrate with a plurality of conductors and forming via openings through the mask material to the conductors for bonding solder balls thereto.

7. A method for fabricating a semiconductor package comprising:

providing a substrate having a first surface and a second surface;

providing a pattern of conductors on the first surface;

forming a first mask on the first surface comprising a plurality of via openings to the conductors;

forming a second mask on the second surface comprising an opening therein defining a die attach area on the substrate; and

attaching a semiconductor die directly to the die attach area.

8. The method of claim 7 further comprising wire bonding the die to the conductors.

9. The method of claim 7 wherein the first mask and the second mask comprise a same photoimageable material.

10. A method for fabricating a semiconductor package comprising:

providing a substrate having a first surface and a second surface;

providing a pattern of conductors on the first surface;

providing a die attach area on the second surface;

5 depositing a photoimageable mask material on the first surface and on the conductors;

depositing the photoimageable mask material on the second surface and on the die attach area;

10 exposing and developing the mask material on the first surface to form a first mask having a plurality of via openings to the conductors;

exposing and developing the mask material on the second surface to form a second mask having an opening to the die attach area; and

15 attaching a semiconductor die directly to the die attach area.

20 11. The method of claim 10 further comprising providing the substrate with a second opening and wire bonding wires through the second opening to the die and to the conductors.

25 12. The method of claim 10 further comprising encapsulating the die in an encapsulating resin.

30 13. The method of claim 10 further comprising placing solder balls in the via openings and bonding the solder balls to ball bonding pads on the conductors.

14. The method of claim 10 further comprising wire bonding the die to the conductors.

15. A method for fabricating a semiconductor package comprising:

providing a substrate having a first surface and a second surface;

providing a pattern of conductors on the first surface, the conductors comprising a plurality of ball bonding pads;

5 substantially covering the first surface and the second surface with a photoimageable mask material;

exposing and developing the mask material on the first surface to form a first mask having a plurality of via openings to the ball bonding pads;

10 exposing and developing the mask material on the second surface to form a second mask having an opening to the substrate defining a die attach area;

attaching a semiconductor die directly to the die attach area; and

15 placing solder balls in the via openings and bonding the balls to the ball bonding pads.

16. The method of claim 15 further comprising providing the conductors with wire bonding pads and wire bonding the die to the wire bonding pads.

20 17. The method of claim 15 wherein the mask material comprises a resist.

25 18. The method of claim 15 wherein attaching the die comprises forming an adhesive layer between the die and substrate.

19. The method of claim 15 further comprising encapsulating the die in an encapsulating resin.

30 20. The method of claim 15 wherein the substrate includes a second opening in the die attach area and the die is placed face down on the substrate and wire bonded through the second opening to the conductors.

21. A semiconductor lead frame comprising:  
a substrate having a first surface and a second surface;  
a plurality of conductors formed on the first surface;  
5 a first mask formed on the first surface comprising a plurality of via openings to the conductors; and  
a second mask formed on the second surface comprising an opening defining a die attach area on the substrate.

10 22. The lead frame of claim 21 further comprising a plurality of die bonding pads on the conductors aligned with the via openings.

15 23. The lead frame of claim 21 further comprising a second opening through the substrate for wire bonding the die to the conductors.

24. A substrate for fabricating a semiconductor package comprising:

20 a plurality of conductors formed on a first surface of the substrate, the conductors comprising a plurality of ball bonding pads;

a first mask formed on the first surface comprising a plurality of via openings to the ball bonding pads; and

25 a second mask substantially covering a second surface of the substrate, and including an opening there through defining a die attach area on the substrate.

30 25. The substrate of claim 24 further comprising a semiconductor die adhesively bonded to the die attach area.

26. The substrate of claim 25 wherein the die attach area has an outline corresponding to an outline of the die.



27. A substrate for a semiconductor package comprising:  
a first surface on the substrate and an opposing second surface on the substrate, the second surface having a die attach area thereon;

5 a plurality of conductors formed on the first surface, each conductor comprising a wire bonding pad and a ball bonding pad;

10 a first mask formed on the first surface comprising a plurality of via openings aligned with selected ball bonding pads on the conductors and a first opening exposing selected wire bonding pads on the conductors; and

a second mask substantially covering the second surface and including a second opening there through to the die attach area.

15 28. The substrate of claim 27 wherein the substrate comprises a third opening there through for wire bonding a die to the wire bonding pads.

20 29. The substrate of claim 27 wherein the first mask and the second mask comprise a photoimageable dielectric material.

25 30. A semiconductor package comprising:

a substrate having a first surface and a second surface;

a plurality of conductors formed on the first surface, the conductors comprising a plurality of ball bonding pads;

a first mask formed on the first surface comprising a plurality of via openings to the ball bonding pads;

30 a second mask substantially covering the second surface and including an opening there through defining a die attach area on the substrate;

a semiconductor die attached to the die attach area in electrical communication with the conductors; and

a plurality of solder balls placed in the via openings and bonded to the ball bonding pads.

5        31. The package of claim 30 further comprising an encapsulating resin on the substrate encapsulating the die.

32. The package of claim 30 wherein the die is wire bonded to the conductors.

10        33. The package of claim 33 further comprising an adhesive layer attaching the die to the die attach area.

34. A semiconductor package comprising:

15        a substrate comprising a first surface and an opposing second surface having a die attach area thereon;

      a plurality of conductors formed on the first surface, each conductor comprising a wire bonding pad and a ball bonding pad;

20        a first mask formed on the first surface comprising a plurality of via openings aligned with selected ball bonding pads on the conductors and a first opening exposing selected wire bonding pads on the conductors;

25        a second mask substantially covering the second surface and including a second opening there through to the die attach area;

      a semiconductor die adhesively bonded to the die attach area and wire bonded to the conductors; and

      an encapsulating resin formed on the die and substrate.

30        35. The package of claim 34 further comprising a third opening in the substrate for wire bonding the die to the conductors.



## ABSTRACT

5        A method for fabricating a BGA package is provided. The  
method includes the step of providing a substrate having a  
first surface with a pattern of conductors thereon, and an  
opposing second surface with a die attach area thereon. A  
first solder mask is formed on the first surface with via  
10 openings to ball bonding pads on the conductors. A second  
solder mask is formed on the second surface with an opening  
on the die attach area. The opening in the second solder  
mask permits a die to be placed through the opening and  
adhesively bonded directly to the substrate. The die can  
15 then be wire bonded to the conductors and encapsulated in an  
encapsulating resin. In addition solder balls can be placed  
in the via openings and bonded to the ball bonding pads.

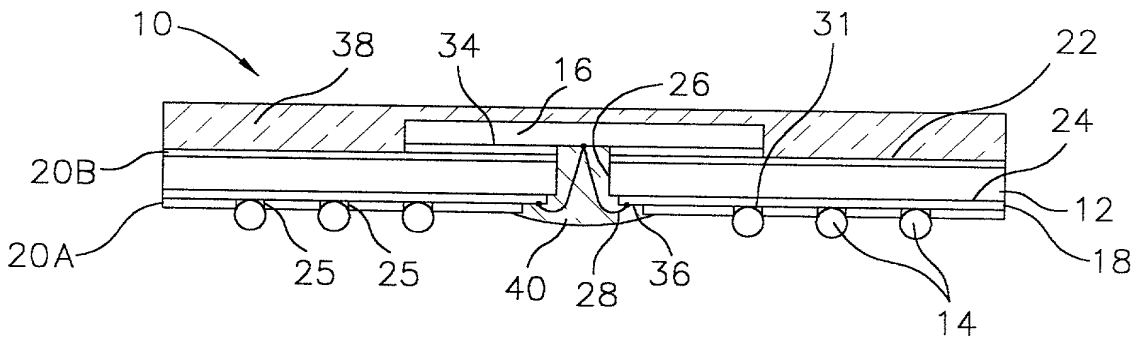


FIGURE 1A  
(PRIOR ART)

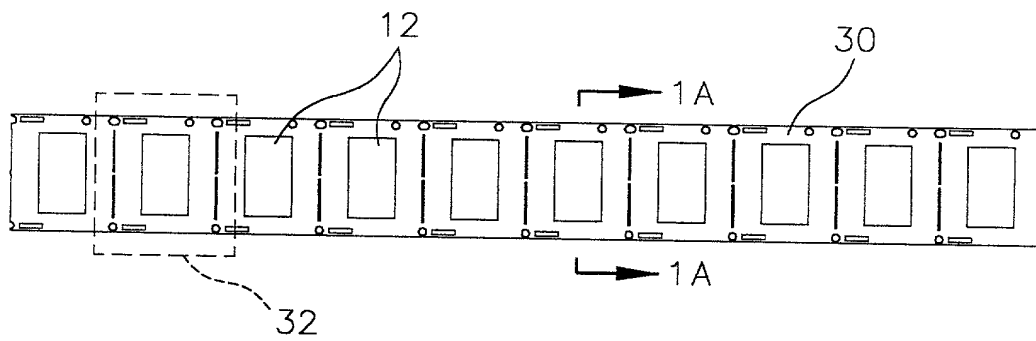
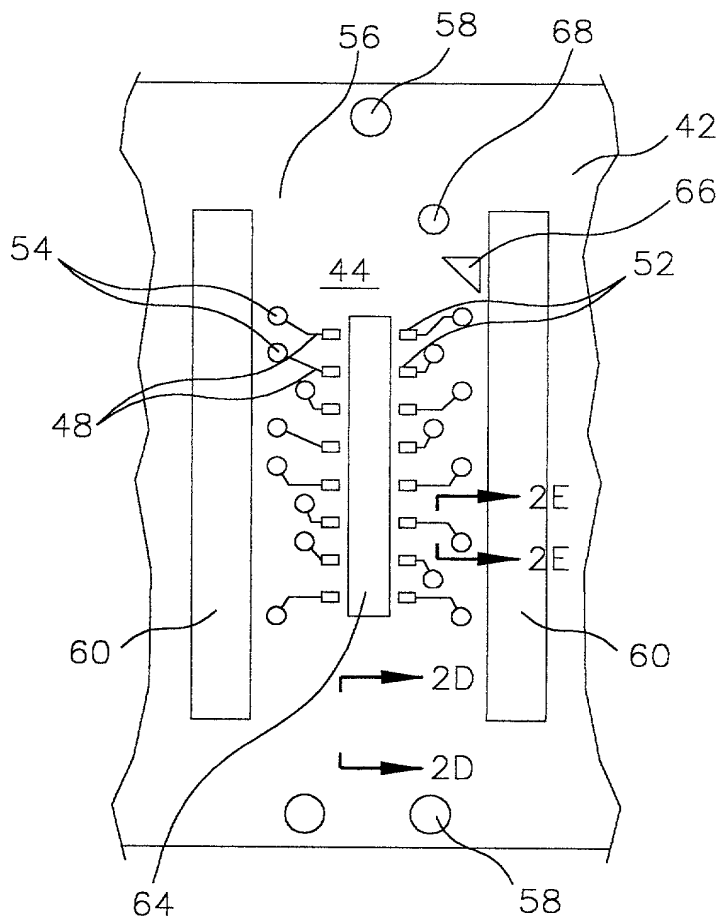
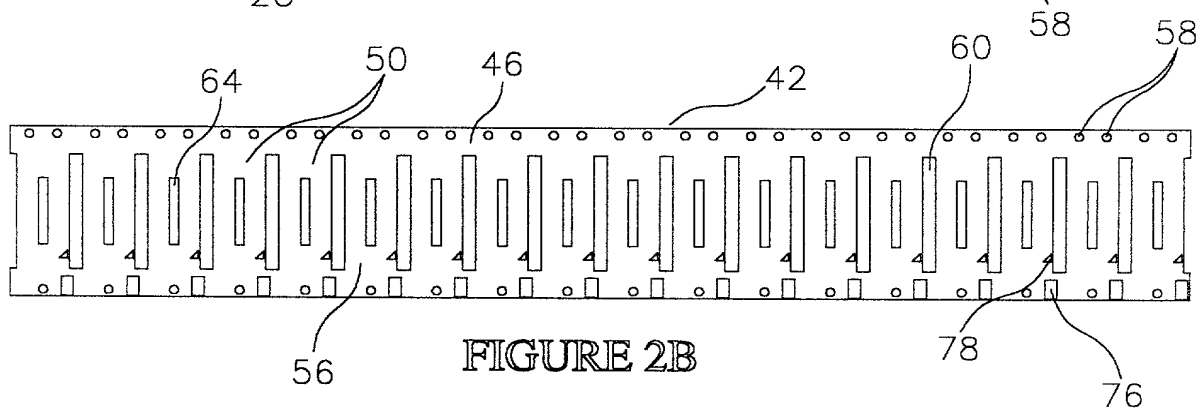
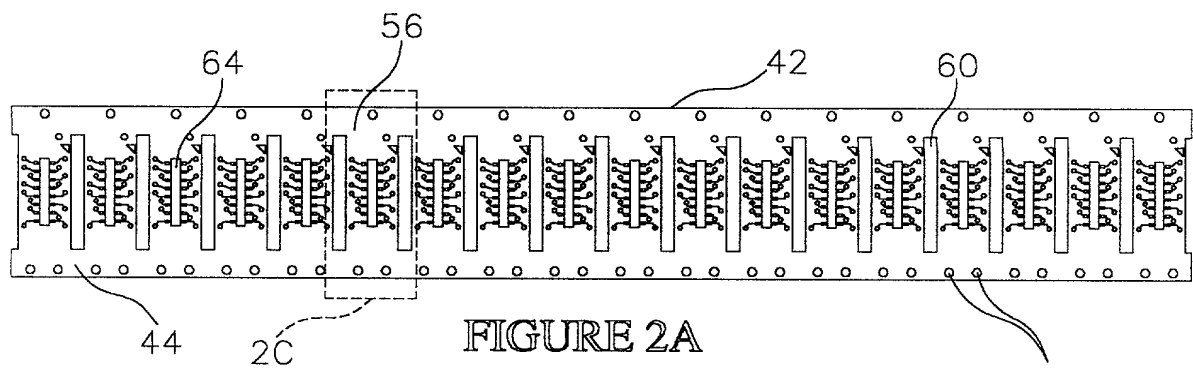


FIGURE 1B  
(PRIOR ART)



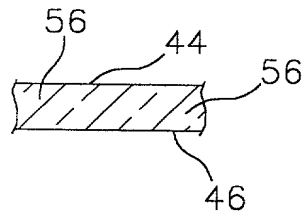


FIGURE 2D

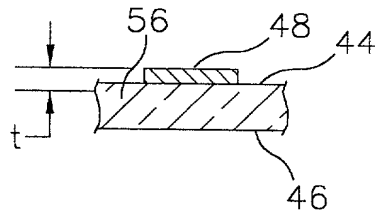


FIGURE 2E

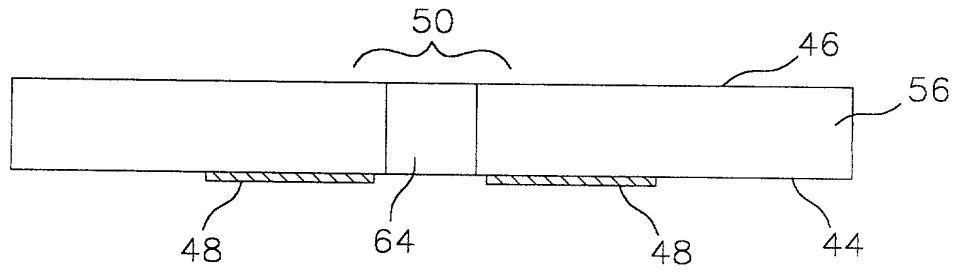


FIGURE 3A

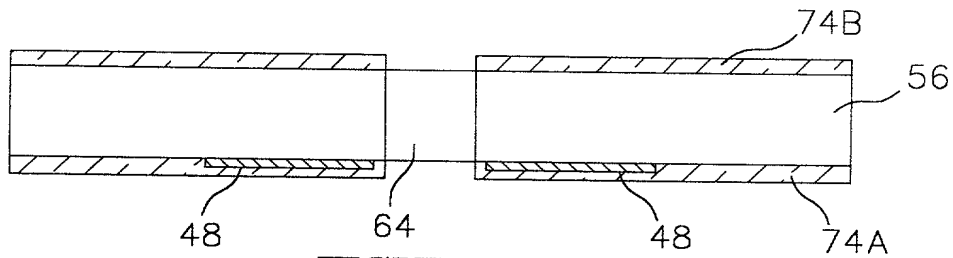


FIGURE 3B

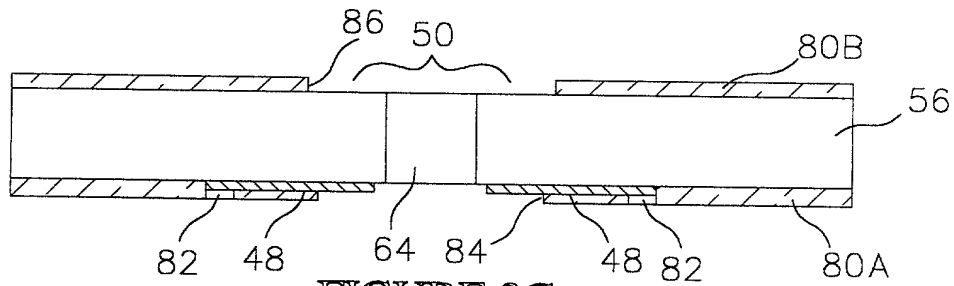


FIGURE 3C

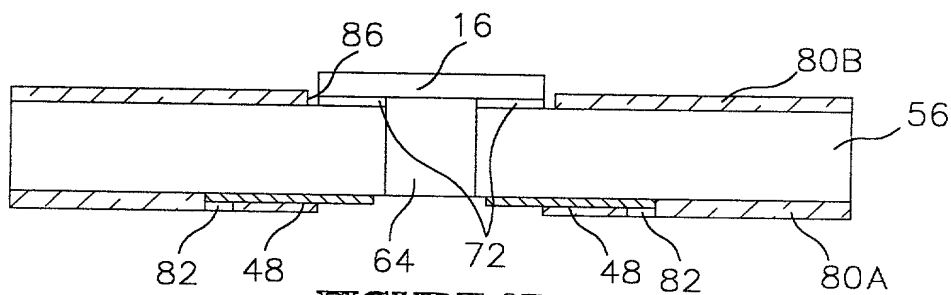
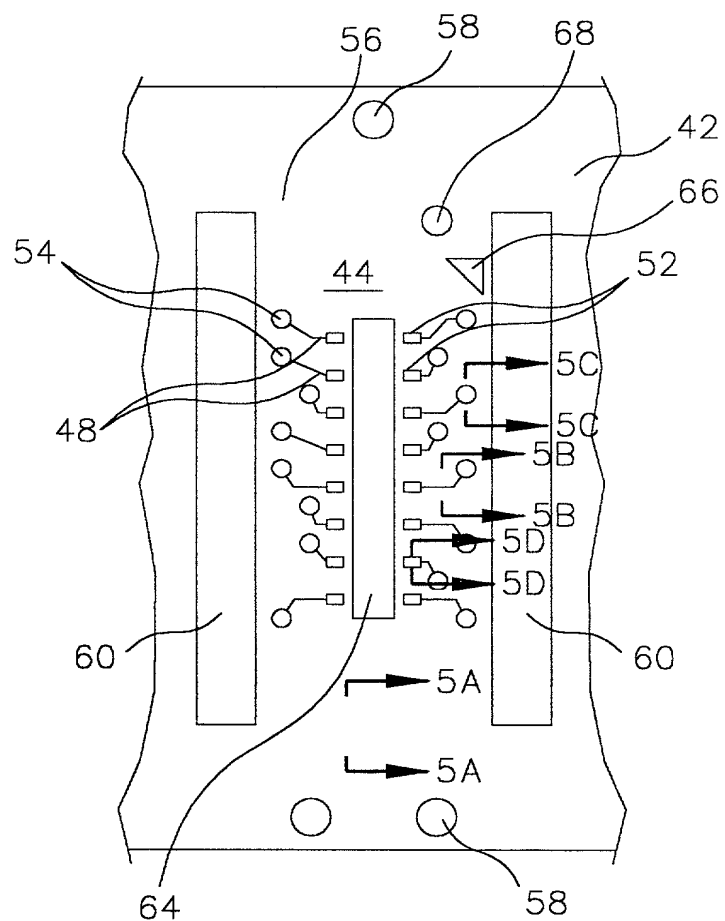
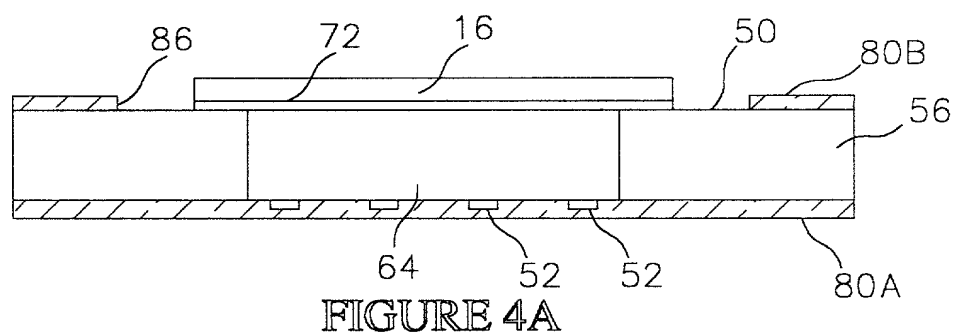
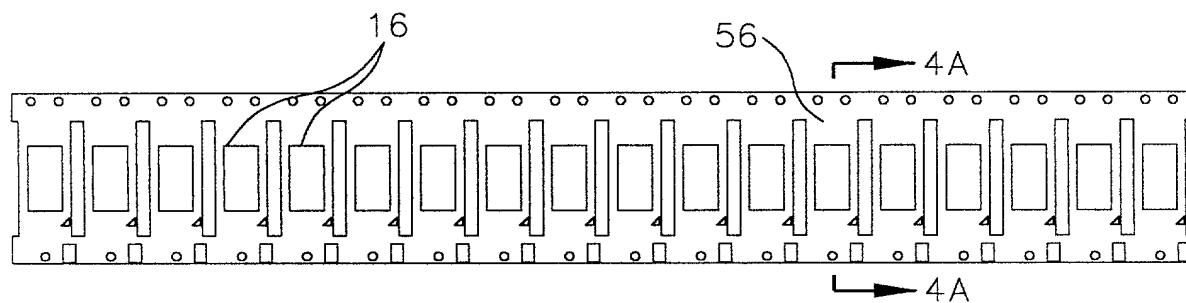


FIGURE 3D





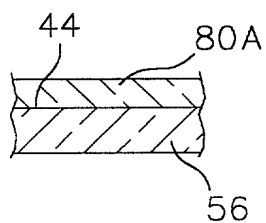


FIGURE 5A

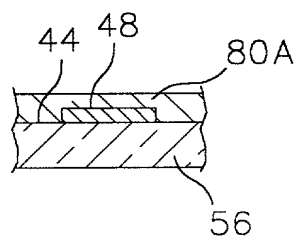


FIGURE 5B

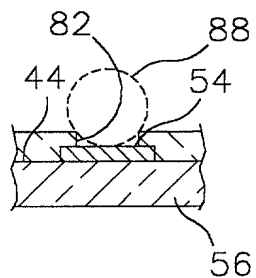


FIGURE 5C

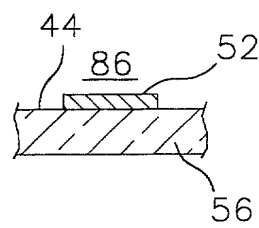


FIGURE 5D

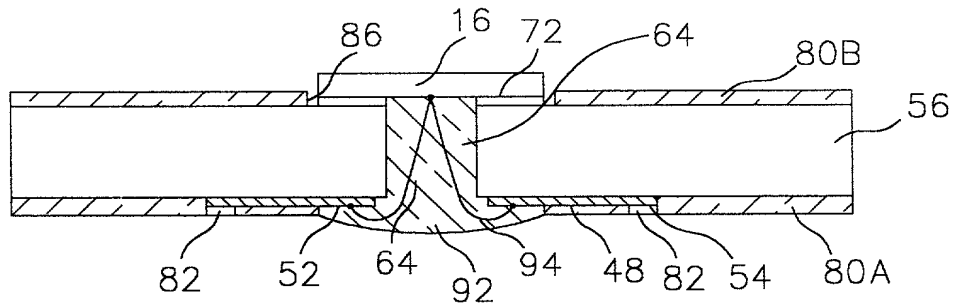


FIGURE 6A

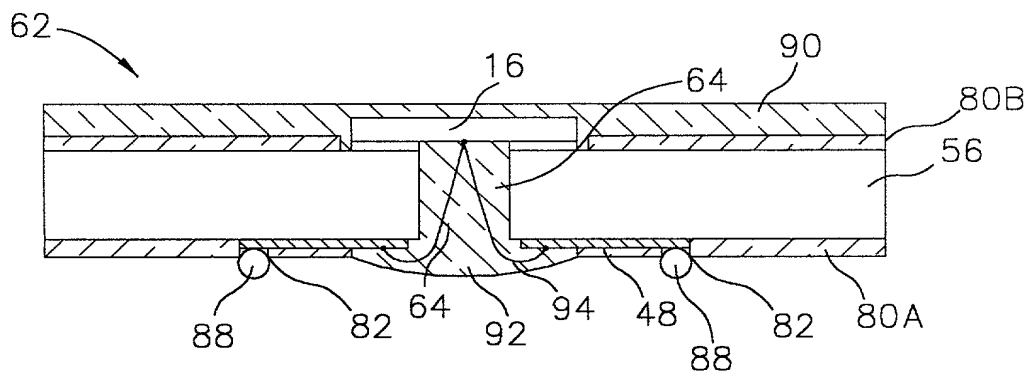


FIGURE 6B

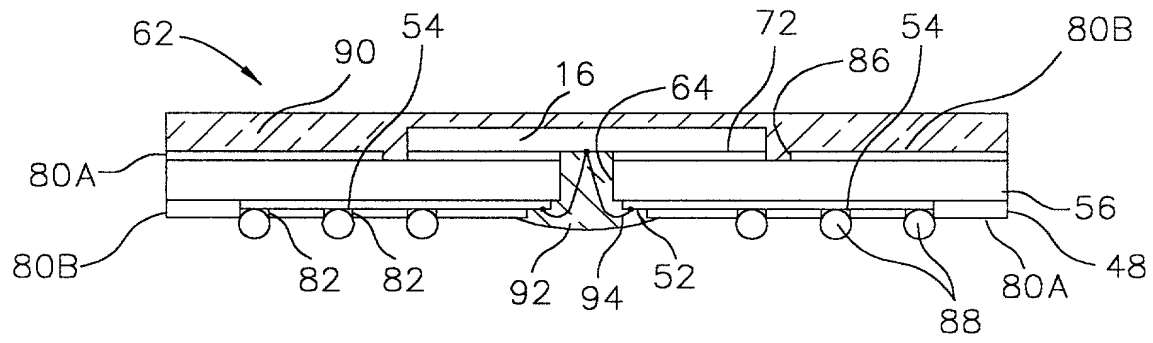


FIGURE 7

**DECLARATION AND POWER OF ATTORNEY  
FOR PATENT APPLICATION  
(Joint Inventors)**

---

We as the below named inventors, declare that:

Our residences, post office addresses and citizenships are as stated below next to our names.

We believe we are the original, first and joint inventors of the subject matter which is claimed and for which patent is sought on the invention entitled:

**METHOD FOR FABRICATING BGA PACKAGE USING SUBSTRATE  
WITH PATTERNED SOLDER MASK OPEN IN DIE ATTACH AREA**

the specification of which (check one)

☒ is attached hereto.

☐ was filed on \_\_\_\_\_ as Application  
Serial No. \_\_\_\_\_.

and was amended on (if applicable) \_\_\_\_\_.

We hereby state that we have reviewed and understand the contents of the above identified specification, including the claims, as amended by any amendment referred to above.

We acknowledge the duty to disclose information which is material to the examination of this application in accordance with Title 37, Code of Federal Regulations, Sec. 1.56(a).

We hereby claim foreign priority under Title 35, United States Code, Sec. 119 of any foreign application(s) for patent or inventor's certificate listed below and have also identified below any foreign application for patent or inventor's certificate having a filing date before that of the application on which priority is claimed: NONE

We hereby claim the benefit under Title 35, United States Code, Sec. 120 of any United States application(s) listed below and, insofar as the subject matter of each of the claims of this application is not disclosed in the prior United States application in the manner provided by the first paragraph of Title 35, United States Code, Sec. 11, we acknowledge the duty to disclose material information as defined in Title 37, Code of Federal Regulations, Sec. 1.56(a) which occurred between the filing date of the prior application and the national or PCT international filing date of this application: NONE

**POWER OF ATTORNEY:** We hereby appoint as our attorneys, STEPHEN A. GRATTON, Registration No. 28,418; MICHAEL L. LYNCH, Registration No. 30,871; and LIA M. DENNISON, Registration No. 34,095, with full power of substitution and revocation, to prosecute this application and to transact all business in the Patent and Trademark Office connected therewith. All correspondence and telephonic communications should be directed to:

STEPHEN A. GRATTON  
2764 South Braun Way  
Lakewood, CO 80228

Telephone: (303) 989 6353  
Fax: (303) 989 6538

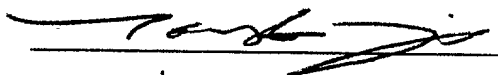
We hereby declare that all statements made herein of our own knowledge are true and that all statements made on information and belief are believed to be true; and further that these statements were made with the knowledge that willful false statements and the like so made are punishable by fine or imprisonment, or both, under Section 1001 of Title 18 of the United States Code and such willful false statements may jeopardize the validity of the application or any patent issued thereon.

Wherefore, we pray that Letters Patent be granted to us for the invention or discovery described and claimed in the foregoing specification and claims, declaration, power of attorney, and this petition.

INVENTOR'S FULL NAME:

**TONGBI JIANG**

INVENTOR'S SIGNATURE:



DATE OF SIGNATURE:

11/6/98

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